

The History of Tokyo Seimitsu

Providing the Highest-level Technology to Achieve the World's No. 1 Manufacturing

Always Changing. Creating the Future. Onward Toward an Unrivaled, One-of-a-kind Presence.

Overcoming countless changes and always evolving, Tokyo Seimitsu is delivering precision measuring instruments and semiconductor manufacturing equipment with highest-level technology to provide customers with new possibilities for manufacturing activities. Overflowing with curiosity and pride, we will constantly tackle the challenges of technical innovation. Our endeavors to spread our fields of activity throughout the world and to keep on meeting new needs that arise will continue without end. Our mission is to achieve the world's best manufacturing activities. We will continue devoting ourselves to manufacturing activities and will hone our skills as we draw up our dreams and move forward step by step, toward the future that we want to shape.

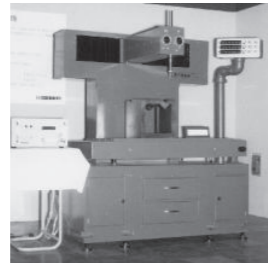
Precision Measuring Instruments



High pressure flow-type air micrometer (1952)



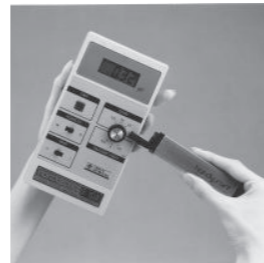
Coordinate measuring machine DELTA SURFCOM (1962)



Coordinate measuring machine DCM-600A (1969)



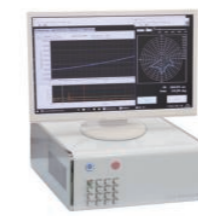
Roundness and cylindrical profile measuring instrument RONDCOM 5A (1979)



Surface texture measuring instrument HANDYSURF E-10A (1984)



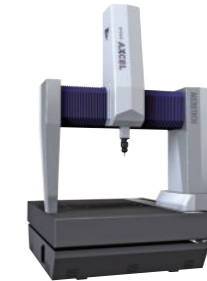
Coordinate measuring machine XYZAX SVA FUSION (2004)



Optical measuring instruments Opt-measure (2012)



Surface texture and contour measuring instrument SURFCOM-NEX (2013)



Coordinate measuring machine XYZAX AXCEL (2017)

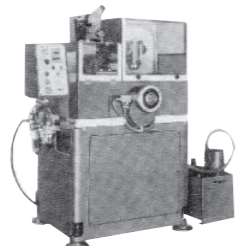


Charge/discharge testing system (2019)

Semiconductor Manufacturing Equipment



Germanium pellet automatic thickness sorting machine (1958)



Dicing machine A-WD-75A (1970)



Probing machine A-PM-3000A (1979)



Dicing machine A-WD-3000A (1984)



Probing machine A-PM-90A (1992)



Polish grinder PG200RM (2000)



Probing machine UF3000 (2003)



CMP ChaMP211 (2009)



High rigid grinder HRG300 (2011)



Dicing blade (2013)

1949

1965

1990

2000

2005

2015

- 1949 ●Tokyo Seimitsu Kogu Co., Ltd. is established
- 1951 ●Commences manufacture and sales of measuring machines using mechanical gauges
- 1952 ●Develops Japan's first flow type air micrometer
- 1955 ●Head office in Mitaka
- 1957 ●Develops Japan's first LVDT type electric micrometer
- Daiichi Seiki Co., Ltd. is established
- 1958 ●Develops Japan's first germanium pellet automatic thickness sorting machine
- 1962 ●Changes name to Tokyo Seimitsu Co., Ltd. ●Stock is listed on the Tokyo Stock Exchange 2nd Section ●Develops surface texture measuring instruments
- 1963 ●Opens Hachioji Plant ●Develops Japan's first internal diameter blade-type wafer slicing machine
- 1964 ●Develops wafer probing machine

- 1967 ●Develops roundness measuring machine
- 1969 ●Opens Tsuchiura Plant ●Tosei Engineering Corp. is established ●Develops Japan's first coordinate measuring machine
- 1970 ●Develops wafer dicing machine
- 1979 ●Markets roundness and cylindrical profile measuring instruments using in-house technology for high-precision rotary air bearings
- 1985 ●New building at Mitaka head office is completed ●Tosei Systems Co., Ltd. is established jointly with Computer Engineering & Consulting (CEC) Ltd. as a software development company
- 1986 ●Stock is listed on the Tokyo Stock Exchange 1st Section
- 1987 ●Research Laboratory is established
- 1988 ●Introduces Group Leader system
- 1989 ●Tokyo Seimitsu Europe GmbH (Germany) is established ●Tokyo Seimitsu America, Inc. (US) is established

- 1992 ●ACCURETECH Service Center Co., Ltd. (South Korea) is established ●Changes name of Daiichi Seiki Co., Ltd. to Micro Technologies Co., Ltd.
- 1994 ●Hachioji Plant and Tsuchiura Plant acquire ISO 9001 certification ●Hachioji Plant attains certification as certified length measurement laser calibration business operator under the traceability system of the Measurement Act ●Beijing Representative Office is established ●Tokyo Seimitsu (Malaysia) Sdn. Bhd. is established
- 1995 ●Tsuchiura Plant attains certification as a certified block gauge calibration business operator under the traceability system of the Measurement Act ●ACCURETECH America, Inc. and ACCURETECH Manufacturing Company (US) are established ●Enters into partnership with Carl Zeiss (Germany) in the field of precision measuring instruments
- 1996 ●Technical Center is established in Hsinchu, Taiwan
- 1997 ●Establishes principles for product development ●Tokyo Seimitsu (Singapore) Pte. Ltd. is established
- 1998 ●Establishes MOTTO ●Hachioji Plant and Tsuchiura Plant acquire ISO 14001 certification
- 1999 ●ACCURETECH Finance Co., Ltd. is established

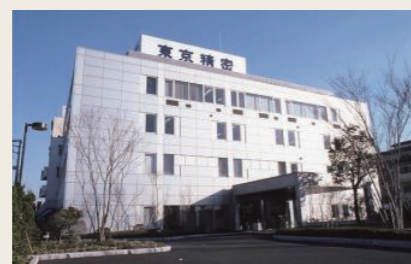
- 2001 ●Introduces corporate brand "ACCURETECH" ●Completes new Hachioji Main Plant Building (ACCT Tower) ●Tosei Box Corp. is established
- 2002 ●Introduces In-House Company System

- 2005 ●New Hachioji Plant and Tsuchiura Plant are completed ●Renews partnership agreement with Carl Zeiss (Germany) for another 5 years
- 2007 ●ACCURETECH Korea, Co., Ltd. is established ●MAHOH DICING MACHINE receives Chairman's Award of the Japan Machinery Federation at the 27th JMF Awards for Energy Efficient Machinery ●Tsuchiura Plant attains certification as certified length measurement laser calibration and coordinate measuring machine fixed calibration business operator under the traceability system of the Measurement Act
- 2008 ●Tsuchiura Metrology Center opens ●Tsuchiura CMM building is completed ●Enters into technical tie-up with Mitaka Kohki Co., Ltd. on non-contact metrology
- 2009 ●Accretech America Inc. is established
- 2010 ●Head office moves to Hachioji
- 2011 ●Semiconductor Company Hachioji Plant No. 5 is completed ●Hachioji Metrology Center opens
- 2012 ●Begins blade business acquired from Mitsubishi Materials Corporation ●ACCURETECH Application Center is established to address diversification of device processes

- 2015 ●Changes name of Tokyo Seimitsu (Thailand) Co., Ltd. to Accretech (Thailand) Co., Ltd.
- 2016 ●Semiconductor Company Hachioji Plant No. 6 is completed
- 2017 ●Issues ACCURETECH Declaration on Promotion of Women's Participation and Advancement ●Collaborates with Panasonic Factory Solutions Co., Ltd. on laser grooving devices for proliferation of plasma dicing method
- 2019 ●Accretech Powerpro System Co., Ltd. is established (acquires shares of Fujitsu Telecom Networks Fukushima Limited, changes name) ●ACCURETECH SBS Inc., ACCURETECH SBS UK Ltd. are established (Subsidiary Tosei Engineering Corp. acquires balancer business and UK subsidiary from Schmitt Industries, Inc.)
- 2020 ●MI building of Tsuchiura Plant is completed ●Opens semiconductor business department of Vietnamese subsidiary ●Conversion of Accretech Powerpro System Co., Ltd. (previous Fujitsu Telecom Networks Fukushima Limited) to wholly owned subsidiary is completed



Tokyo Seimitsu Kogu Co., Ltd. (1949)



Head office in Mitaka (1985)



Hachioji ACCT Tower (2001)